## Supporting Information for

## A Universal Growth Method for High Quality Phase-Engineered Germanium Chalcogenide Nanosheets

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Fig. S1. Schematic diagram of the experimental setup and the controllable growth process of Germanium

chalcogenide.



**Fig. S2.** (a) Phase diagram for the growth of GeSe and GeSe<sub>2</sub>. (b-d) Typical growth results under the growth conditions marked with 1, 2 and 3 in (a), respectively



Fig. S3. (a) Phase diagram for the growth of GeS and GeS<sub>2</sub>. (b-d) Typical growth results under the growth

conditions marked with 1, 2 and 3 in (a), respectively



Fig. S4. SEM images and the element mapping of GeSe and GeSe<sub>2</sub>. (a)SEM image of GeSe<sub>2</sub>. Scale bar is 5  $\mu$ m. (b) elemental mapping in the pink rectangle region of the GeSe<sub>2</sub>. (c) SEM image of GeSe. Scale bar is 5  $\mu$ m. (d) elemental mapping in the pink rectangle region of the GeSe.



Fig. S5. SEM images and the element mapping of GeSe and GeSe<sub>2</sub>. (a)SEM image of GeSe<sub>2</sub>. Scale bar is 5  $\mu$ m. (b) elemental mapping in the pink rectangle region of the GeSe<sub>2</sub>. (c) SEM image of GeSe. Scale bar is 5  $\mu$ m. (d) elemental mapping in the pink rectangle region of the GeSe images and the element mapping of GeSe and GeSe<sub>2</sub>.



**Fig. S6.** XPS spectra of GeSe<sub>2</sub> (a,b) and GeSe (c,d). The core line signals of Ge 3d and Se 3d located at 31.5 eV and 55.0 eV for GeSe<sub>2</sub>, while they are situated at 30.0 eV (Ge 3d) and 54.1 eV (Se 3d) for GeSe.



**Fig. S7.** XPS spectra of GeS<sub>2</sub> (a,b) and GeS (c,d). There are peaks of GeS<sub>2</sub> located at 32.3 eV (Ge 3d, GeS<sub>2</sub>), 163.1 eV (S  $p_{3/2}$ , GeS<sub>2</sub>) and 164.2 eV (S  $2p_{1/3}$ , GeS<sub>2</sub>) in Fig. S7(a) and S7(b). Figure S7(c) and S7(d) show the binding energy of Ge<sup>2+</sup> (30.9 eV), Ge<sup>4+</sup> (32.1 eV), S  $2p_{3/2}$  (162.1 eV) and S  $2p_{1/2}$  (163.1 eV) in GeS.



Fig. S8. Low-magnification TEM image of  $GeSe_2(a)$ , GeSe(b),  $GeS_2(c)$  and GeS(d).



Fig. S9. EDS spectra of GeSe(a), GeSe<sub>2</sub>(b), GeS(c) and GeS<sub>2</sub>(d). The EDS spectrum of GeSe (a) shows that the Ge/Se ratio is ~1:1. The EDS spectrum of GeSe<sub>2</sub> (b) shows that the Ge/Se ratio is ~1:2. The EDS spectrum of GeS (c) shows that the Ge/S ratio is ~1:2. The EDS spectrum of GeS<sub>2</sub> (d) shows that the Ge/S ratio is ~1:2.



Fig. S10. Raman feature of GeS<sub>2</sub>. (a) Raman spectrum of GeS<sub>2</sub>. (b) Raman mapping of GeS<sub>2</sub>. The

inset is the corresponding optical image. Scale bar is 5  $\mu$ m.



Fig. S11. Low-magnification TEM image of  $GeS_2(a)$  and the corresponding selected area electron diffraction pattern(b). Because of the instability of the grown  $GeS_2$  under high energy electron beam, the high-resolution TEM image is unavailable.



Fig. S12. AFM image of GeSe and GeSe<sub>2</sub>. (a)AFM image of GeSe<sub>2</sub>. (b)AFM image of GeSe.



Fig. S13. Temperature-dependence of the phonon peak position of the  $A_{g}^{3}$  mode at 150 cm<sup>-1</sup> of

GeSe nanobelt.



**Fig. S14.** (a) Angle - dependent Raman spectra of GeSe at angle ranging from 180° to 360°. (b) Angle-resolved Raman scattering intensities of  $B_{3g}$  modes under parallel configureuration. (c) Angleresolved Raman scattering intensities of  $A_{3g}^{3}$  modes under parallel configureuration.



Fig. S15. The absorption measurements of the grown germanium chalcogenide nanosheets. (a) The transmission of the transparent glass sheet. (b-d) The absorption spectra of GeS (b), GeSe (c) and  $GeSe_2$  (d)



Fig. S16. (a) Schematic structure of the GeS photodetector. (b) Optical image of the device. Upper right is the corresponding AFM image, scale bar is 20  $\mu$ m. (c)  $I_{ds}$ - $V_{bg}$  transfer curves at various  $V_{ds}$  values. (d)  $I_{ds}$ - $V_{ds}$  output characteristics of the device at gate voltage varying from -60 to 60 V.



**Fig. S17.** Optoelectronic characteristics of GeS-based device. (a) Output curves of GeS under different 520 nm irradiation intensities at  $V_{bg}$ = -60 V. (b) Transfer curves in the dark and under diverse 520 nm laser intensities at  $V_{ds}$  = 1 V. (c-d) Irradiation power dependence of photocurrent (c), photoresponsivity (d) and detectivity (e) of GeS at  $V_{ds}$ =1 V. (f) The on/off switching of the GeS. The calculated photoresponsivity and dectectivity of GeS are 0.005 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup>, 6.1 A/W and 9.3×10<sup>9</sup> Jones.



Fig. S18. Optoelectronic characteristics of  $GeSe_2$ -based device. (a) Schematic structure of the  $GeSe_2$  photodetector. (b) Optical image of the device. Upper right is the corresponding AFM image, scale bar is 20  $\mu$ m. (c) I-V curves of  $GeSe_2$  under dark and 405 nm irradiation. (d) The on/off switching of the  $GeSe_2$ . The calculated photoresponsivity and dectectivity of  $GeSe_2$  are  $1.5 \times 10^{-6}$  A/W and  $6.2 \times 10^4$  Jones.



Fig. S19. Optoelectronic characteristics of  $GeS_2$ -based device. (a)Output curves of  $GeS_2$  under various

gate voltages. (b) I-V curves of  $GeS_2$  under dark and 405 nm irradiation.



Fig. S20. (a) Output curves of GeSe on  $HfO_2/Si$  and  $SiO_2/Si$  substrate. (b) Transfer curves of GeSe

on  $HfO_2/Si$  and  $SiO_2/Si$  substrate.

Table. S1. Comparison of grown GeSe-based photodetector performance with other reported 2D

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Material	Fabrication	Spectral	Responsivit	Detectivity	Rise time	Ref
	Mathod	region	у	[Jones]	[ms]	
		0	[Å W <sup>-1</sup> ]		2 3	
SnSe <sub>2</sub>	CVD	NIR	1.9	-	-	22
$SnS_2$	CVD	visible	261	$1.9  imes 10^{10}$	20	46
MoS <sub>2</sub>	CVD	visible	0.057	1010	0.07	51
MoSe <sub>2</sub>	CVD	visible	93.7	-	400	53
$WS_2$	CVD	visible	9.2×10 <sup>-5</sup>	-	5.3	54
ReS <sub>2</sub>	CVD	visible	16.14	-	105	55
GaTe	CVD	UV-visible	0.03	-	54	56
$HfS_2$	CVD	UV-visible	$2.8 \times 10^{3}$	-	55	49
$HfS_3$	CVD	visible	0.11	-	<400	57
$ZrS_3$	CVD	visible	0.53	-	<400	57
$In_2Se_3$	CVD	visible	578	$6 \times 10^{12}$	20	52
$ReS_{2(1-x)}Se_{2x}$	CVD	Visible-NIR	0.25	-	15	50
GeSe	CVD	visible	$9.3 \times 10^{3}$	-	48	23
GeSe	CVD	visible	$1.16  imes 10^{5}$	9.82×1012	11	This work

semiconductors prepared by CVD